

PATENT



Attorney Doc. No.: N1085-00222/TSMC2003-0413

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application No.: 10/810,385

Confirmation No.: 8603

In re application of: Ming Lu et al.

Filed: March 26, 2004

Technology Center/Art Unit: 1756

Examiner: John S. Ruggles

Docket No.: N1085-00222(TSMC2003-0413)

Customer No.: 54657

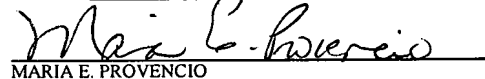
Title: REPAIR OF PHOTOLITHOGRAPHY
MASK BY SUB-WAVELENGTH
ARTIFICIAL GRATING TECHNOLOGY

CERTIFICATE OF MAILING/FACSIMILE TRANSMISSION
PURSUANT TO 37 C.F.R. §1.8

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AMENDMENT

Commissioner:

Responsive to the Non-Final Office Action dated **February 5, 2007**, please amend the
above-identified application as follows:

Amendments to the Drawings are reflected on page 2 of this paper.

Amendments to the Specification appear on page 3 of this paper.

Amendments to the Claims are reflected in the listing of claims which begins on page 4
of this paper.

Remarks/Arguments begin on page 9 of this paper.